INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)			Docket Number (Optional) 81870.0027		Application Number 10/758,692	
			Applicant Michifumi SHODA et al.			
			Filing Date January 15, 2004		Group Art Unit 2872	
		U.S. PATENT	DOCUMENTS			
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
-	F	OREIGN PATE	NT DOCUMENTS	3		
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION (YES/NO)
	Taek CHUNG et al., "Room Tempe Method" Nuclear Instruments and Methods	erature GaAs-Si ar		Bonding By T		rated Bonding
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EXAMINER	DATE CONSIDERED .					
EXAMINER: If	nitial if citation considered, whether o and not considered. Include copy of	r not citation is in o	conformance with MPE	EP § 609; Drav	w line through ci	tation if not in